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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Rainer LOESCH, et al.
Serial No. : 09/750,837
Filed : December 28, 2000
Title : CALIBRATED SCALE IN THE NANOMETER RANGE FOR
TECHNICAL DEVICES USED FOR THE HIGH-
RESOLUTION OR ULTRAHIGH-RESOLUTION IMAGING
OF STRUCTURES
Art Unit : 1774
Examiner : Lawrence Ferguson

Commissioner for Patents
Washington, D.C. 20231
BOX AF

I hereby certify that this correspondence is being deposited with the United
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Date: February 19, 2003

Signature:

Linda M. Shudy (Reg. No. 47,084)

AMENDMENT

SIR:

In response to the Office Action having mailing date of October 17, 2002, please
reconsider the above-identified application based on the following.

IN THE CLAIMS:

Please amend without prejudice claim 1 as follows:

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1. (Twice amended) A scale for technical devices which are used for high-resolution or
ultrahigh-resolution imaging of structures, the scale comprising:

a plurality of first material layers having a first thickness, the plurality of first material
layers being one of crystalline and amorphous; and

a plurality of second material layers, the plurality of second material layers being one of
crystalline and amorphous, which are distinguishable from the first material layers when
imaged using high-resolution or ultrahigh-resolution imaging methods, the second material

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